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TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT  
(Under 37 CFR 1.97(b) or 1.97(c))

Docket No.  
10932-US

In Re Application Of: Luc OUELLET, et al.

Serial No.	Filing Date	Examiner	Group Art Unit
09/833,711	13 April 2001		2874

Title: OPTICAL QUALITY SILICA FILMS

Address to:  
Assistant Commissioner for Patents  
Washington, D.C. 20231

37 CFR 1.97 (b)

1.  The Information Disclosure Statement submitted herewith is being filed within three months of the filing of a national application; within three months of the date of entry of the national stage as set forth in 37 CFR 1.491 in an international application; or before the mailing date of a first Office Action on the merits, whichever event occurs last.

37 CFR 1.97 (c)

2.  The Information Disclosure Statement submitted herewith is being filed after three months of the filing of a national application, or the date of entry of the national stage as set forth in 37 CFR 1.491 in an international application; or after the mailing date of a first Office Action on the merits, whichever occurred last but before the mailing date of either:

1. a Final Action under 37 CFR 1.113, or
2. a Notice of Allowance under 37 CFR 1.311,

whichever occurs first.

Also submitted herewith is:

a certification as specified in 37 CFR 1.97(e);

OR

the fee set forth in 37 CFR 1.17(p) for submission of an Information Disclosure Statement under 37 CFR 1.97(c).

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Payment of Fee

(Only complete if Applicant elects to pay the fee set forth in 37 CFR 1.17(p))

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34,519

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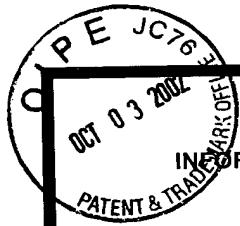
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**INFORMATION DISCLOSURE CITATION**  
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10932-US

SERIAL NO.  
09/833,711

**APPLICANT(S)**

**FILING DATE**  
13 April 2001

GROUP  
2874

## U.S. PATENT DOCUMENTS

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## FOREIGN PATENT DOCUMENTS

**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

		(1) "Stress in PSG and nitride films as related to film properties and annealing", T.H. Tom Wu et al., Solid State Technology, 35 (1992), No. 5, pages 65-72.
		(2) "Characteristics of low-temperature and low-energy plasma-enhanced chemical vapor deposited SiO <sub>2</sub> ", J. Appl.Phys., Vol. 74, No. 4, 1993, pages 2638-2648.
		(3) "Plasma-activated deposition and properties of phosphosilicate glass film", Akira Takamatsu et al., Journal of the Electrochemical Society, 1984, Vol. 131 No. 8, pages 1865-1870. (4) "Controlled oxidation of silane", K. Strater, RCA Electronic Components, pages 618-629.
EXAMINER	DATE CONSIDERED	

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not wished. Include copy of this form with next communication to applicant.

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